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09/88791 09/88791	Class	ISSUE CLASSIFICATION

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·~.	APPLICATION NO.	CONT/PRIOR	CLASS	SUBCLASS	ART UNIT	EXAMINER	34
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Jack Hwang Mitchell Taylor

Method of making a semiconductor transistor by implanting ions into a gate dielectric layer thereof

UNIGINAL	ONE SUBCLASS PER BLOCK)
CLASS	(ONE SUBCLASS PER BLOCK)
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TERMINAL	DRAWINGS			CLAIMS ALLOWED		
DISCLAIMER	Sheets Drwg.	Figs. Drwg.	Print Fig.	Total Claims	Print Claim for O.G.	
The term of this patent			NOTICE OF ALI	LOWANCE MAILED		
subsequent to (date) has been disclaimed.	(Assistant Examiner) (Date)		4,9			
The term of this patent shall not extend beyond the expiration date of U.S Patent. No.				ISSUE FEE		
				Amount Due	Date Paid	
1	(Primary	Examiner)	(Date)		·	